Main Options of A8 Prober



- OCR wafer ID reader
- Chuck: high/low/normal temperature
- Support 50µm wafer
- Support Bernoulli arm and chuck
- 3KV high voltage, 300A large current
- Triaxial chuck, pA leakage current
- Real time map data
- One touch contact probing
- PMAI: Probe Mark Auto-Inspection
- PLV: Prober Log Viewer
- RCS: Remote Control System
- DUT Editor & Recipe Editor

A B Automatic Probe Station

Specifications of A8 Automatic Probe Station

		Repeatability:≤±1µm	
	XY axis Resolution: 0.1μm Probing area: 260 * 450 mm	Resolution: 0.1µm	
		Probing area: 260 * 450 mm	
		Maximum speed : 200mm/s	
Main body		Repeatability:≤±1µm	
	Z axis	Resolution: 0.1µm	
		Travel range: 0 ~ 80mm	
		Maximum speed : 80mm/s	
	θaxis	Rotation Range :±10°	
	U dais	Resolution: 0.0001°	
Loader	Cassette / Wafer Size	Ф150mm, Ф200mm	
Monitor		15 inch High-resolution color LCD	
Facility Requirement		Power : 50/60Hz AC 220V, CDA: 0.6 to 0.7Mpa , Vacuum: -70 to -90Kpa	
Dimensions & Weight		W*D*H: 1124mmL*1111mmW*925mmH, 1200 KG (standard).	



SEMISHARE CO., LTD.

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Website





SEMISHARE-A8 Automatic Probe Station

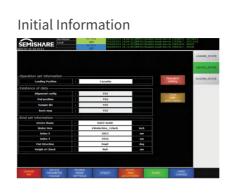
A8 is a new high-power prober with a temperature range from room temperature to +200 °C and supports the measurement of high voltage 3 kV (Tri-axis)/10 kV (coaxial) and 500A. It can test high-power chip characteristics, which can also be tested on thin wafers or TAIKO wafers.

The innovative A8 prober has made new upgrades and improvements in technologies such as automatic wafer loading and unloading, micron-level full closed-loop motion control, automatic wafer contact, accurate visual calibration, high-speed feedback communication, and data information processing. The prober is equipped with a highly stable wafer testing technology.

Product Features

- Super high test precision and test speed, greatly improve productivity benefits
- Micrometer-level full closed-loop motion control
- 24X7 hours on-chip detection
- Small size, light weight and smaller footprint
- High voltage and high current test application
- Bernoulli arm support sheet

Friendly Graphic User Interface



Recipe Parameter Settings

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	PadSearchSetting	Pad Search

Wafer Edge Measurement

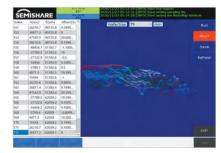




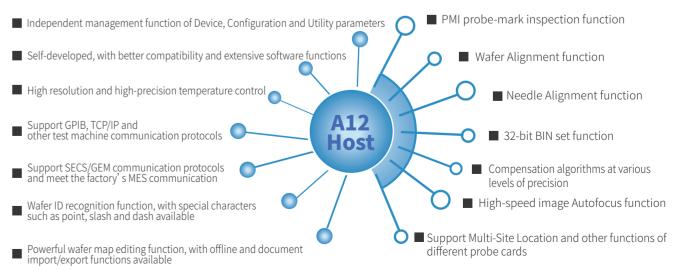
PAD Registration

Wafer ID Reading





Software Functions







Contact Compensation

Multi DUT Location Edit



Index & Z height



Real-time Wafer Map Data

